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(54) Title: METHODS OF MANUFACTURING ELECTROSTATIC CHUCKS

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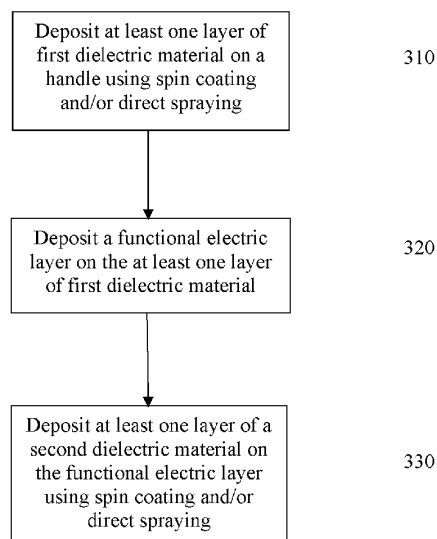


FIGURE 3

(57) Abstract: A method of depositing material to manufacture an electrostatic chuck is provided. The method first deposits at least one layer of a first dielectric material on a handle using spin coating and/or direct spraying method. A functional electric layer is next deposited on the at least one layer of the first dielectric material. Finally, the electrostatic chuck is formed by depositing at least one layer of a second dielectric material on the functional electric layer and the first dielectric material using spin coating and/or direct spraying method.

[Continued on next page]

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